

## X-RAY APPARATUS

Patent Number: JP2004014402  
Publication date: 2004-01-15  
Inventor(s): TAMURA TOMOMI  
Applicant(s): SHIMADZU CORP  
Requested Patent: JP2004014402  
Application Number: JP20020168819 20020610  
Priority Number(s):  
IPC Classification: H05G1/00; H01J35/14; H05G1/26  
EC Classification:  
Equivalents:

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### Abstract

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**PROBLEM TO BE SOLVED:** To provide an X-ray apparatus capable of well adjusting the electron beam axis in an X-ray tube.

**SOLUTION:** A first-stage aperture 25 comprising through holes 31a-31d as a singular part which is used for detecting the position of electron beam is positioned around the axis of the electron beam B connecting an electron gun 11 to a target 13 in an open type X-ray tube 1. A control part 41 scans and controls a deflector 15 so that the through holes 31a-31d of the first stage aperture 25 are irradiated with the electron beam B. The electron beam B is adjusted based on the deflection amount of the optical axis of the electron beam B of the deflector 15 and the X-ray volume or an X-ray image acquired by detecting the X-ray occurring in the through holes 31a-31d of the first-stage aperture 25 with an I/I tube 2. So the positional information about the electron beam B is acquired, and the electron beam B is allowed to pass a desired position, for well adjusting.

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